## **Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

## **Listing of Claims:**

- 1. (Currently Amended) A method for creating a pattern on a substrate, the method comprising the step of:
  - (a) imprinting a first pattern on the substrate; and
- (b) imprinting a second substantially similar pattern that is intentionally mis-registered in a pre-defined manner with regard to the first pattern so that the combination of the first and second patterns eauses a causes continuous, systematic variation in a final size and pre-defined variations in final sizes of defined elements across the substrate consistent with the predefined misregistration so that at least two or more of the defined elements have different dimensions.
- 2. (Original) The method as in claim 1, wherein step (b) includes providing the elements as structures used for an image sensor.
- 3. (Original) The method as in claim 2, wherein step (b) includes providing the element as an aperture.
- 4. (Original) The method as in claim 1, wherein step (b) includes providing the element as a micro-lens.
- 5. (Original) The method as in claim 1, wherein step (b) includes providing a mask as the substrate, which mask is used as a template for device fabrication.
- 6. (Original) The method as in claim 1, wherein step (b) includes providing a material upon which the device is fabricated as the substrate.

7. (Original) The method as in claim 3, wherein step (b) includes systematically increasing aperture size as the aperture approaches a periphery of the substrate.

## **Discussion Regarding the Drawings:**

Formal drawings are submitted herewith under Separate Letter to the Draftsperson. For the convenience of the Examiner, a copy of the formal drawings are also attached with this amendment.